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RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2815

00862.022205.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yoshiyuki NAGAI et al.

Application No.: 09/839,139

Filed: April 23, 2001

For: LASER OSCILLATION APPARATUS, EXPOSURE APPARATUS,) July 30, 2004
SEMICONDUCTOR DEVICE MANUFACTURING METHOD,)
SEMICONDUCTOR MANUFACTURING FACTORY, AND)
EXPOSURE APPARATUS MAINTENANCE METHOD)

) Examiner: M. Landau

) Group Art Unit: 2815

) Confirmation No.: 1616

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Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment After Final Rejection in the above-identified application.

☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	3	MINUS	32	= 0	x \$9 \$18	\$0.00
INDEP. CLAIMS	2	MINUS	14	= 0	x \$43 \$86	\$0.00
Fee for Multiple Dependent claims \$145/\$290						\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00